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2812 7

PATENT

Attorney Docket No.: SSI-00501

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:) Group Art Unit: 2812

Maximilian A. Biberger, et al.) Examiner:

Serial No.: 09/912,844) **TRANSMITTAL LETTER**

**For: HIGH PRESSURE PROCESSING
CHAMBER FOR
SEMICONDUCTOR SUBSTRATE**

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed please find an Information Disclosure Statement, Certification pursuant to 37 C.F.R. § 1.97(e) for the Information Disclosure Statement, and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. 08-1275. An originally executed duplicate of this transmittal is enclosed for this purpose.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 7-3-02

By: James B. Fenn

Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants

CERTIFICATE OF MAILING (37 CFR § 1.8(a))

I hereby certify that this paper (along with any, referred to as being attached or enclosed) is being deposited with the U.S. Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the: Assistant Commissioner for Patents, Washington D.C. 20231

HAVERSTOCK & OWENS LLP

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Date: 7-5-02 By: Tom D. Russen

v: Frank D. Russon

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In re Application of:) Group Art Unit: 2812

Maximilian A. Biberger, et al. 1

**For: HIGH PRESSURE PROCESSING
CHAMBER FOR
SEMICONDUCTOR SUBSTRATE**

Assistant Commissioner of Patents
Washington, D.C. 20231

Sir:

This certification is being made for the Supplemental Information Disclosure Statement accompanying this certification.

Certification

I hereby certify that the attached six (6) references contained in this information disclosure statement were cited within an International Search Report (ISR) mailed on May 21, 2002. **Accordingly, the references contained in the information disclosure statement were cited in a communication from a foreign patent office in a counterpart application not more than three months prior to the filing of the statement.** 37 C.F.R. 1.97(e)(1).

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CERTIFICATE OF MAILING (37 CFR § 1.8(a))

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HAYERSTOCK & OWENS LLP.

Date: 7-5-02 By: Juan D. Racion

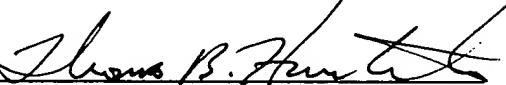
PATENT
Attorney Docket No.: SSI-00501

Identification of Person Making Certification

The person making this certification is the attorney who signs below on the basis of the information in the attorney's file.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 7-3-02

By: 
Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants



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Attorney Docket No.: SSI-00501

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Maximilian A. Biberger *et al.*
Serial No.: 09/912,844
Filed: July 24, 2001
For: **HIGH PRESSURE PROCESSING
CHAMBER FOR
SEMICONDUCTOR SUBSTRATE**

) Group Art Unit: 2812
) Examiner:
) **SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT**
) 162 N. Wolfe Road
) Sunnyvale, CA 94086
) (408) 530-9700

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

Applicants have become aware of the following printed publications which may be material to the examination of this application:

- U.S. Patent No. 5,314,574;
- U.S. Patent No. 5,328,722;
- U.S. Patent No. 5,955,140;
- Japan Publication No. 2000 - 106358;
- PCT Publication No. WO 01/10733 A1 and
- PCT Publication No. WO 01/33615 A3.

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HAVERSTOCK & OWENS LLP.

Date: 7-5-02 By: James D. Larson



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Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 7-3-02

By: Thomas B. Haverstock
Thomas B. Haverstock
Reg. No.: 32,571

Attorneys for Applicants

